

Inventor Information

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Correspondence Information

Correspondence Customer Number:: 25944

Application Information

Title Line One:: METHOD AND APPARATUS FOR ION
Title Line Two:: ATTACHMENT MASS SPECTROMETRY
Title Line Three::
Title Line Four::
Total Drawing Sheets:: 9
Docket Number:: 111522

Continuity Information

>This application is a:: Division of
Application One::
Filing Date::
Patent Number::
which is a:: Division of
>>Application Two::
Filing Date::
Patent Number::

Prior Foreign Applications

Foreign Application One:: JP 2000-401483
Filing Date:: December 28, 2000
Country:: Japan
Priority Claimed:: Yes
Foreign Application Two::
Filing Date::
Country::
Priority Claimed::
Foreign Application Three::
Filing Date::
Country::
Priority Claimed::

Assignee Information

Name of assignee:: ANELVA CORPORATION
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